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**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicants: TETSUKA et al

EXPEDITED PROCEDURE

Serial No.: 10/784,275

Filed: February 24, 2004

For: Plasma Processing Apparatus And Plasma  
Processing Method

Art Unit: 1763

Examiner: R. Zervigon

**AMENDMENT AFTER FINAL ACTION**

Mail Stop: Box AF Amendment (No Fee)  
Commissioner For Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

January 16, 2007

Sir:

The following amendments and remarks are respectfully submitted in connection with the above-identified application, in response to the Office Action dated October 13, 2006. The amendments are listed below and set forth on the following pages.

Amendments to the Claims; and

Remarks are included following the amendments.